



This project has received funding from the European Union's Horizon-INFRA-2023-TECH-01 under GA No 101131435 – iSAS and from the European Union's Horizon 2020 Research and Innovation programme under GA No 101004730 – I,FAST



**SRF cavities  
R&D for  
FCC-ee**  
INFN Accelerators European  
Strategy Program

**RD\_FCC**  
INFN CSNI Experiment

**SOMARA**  
INFN CSN5 Experiment

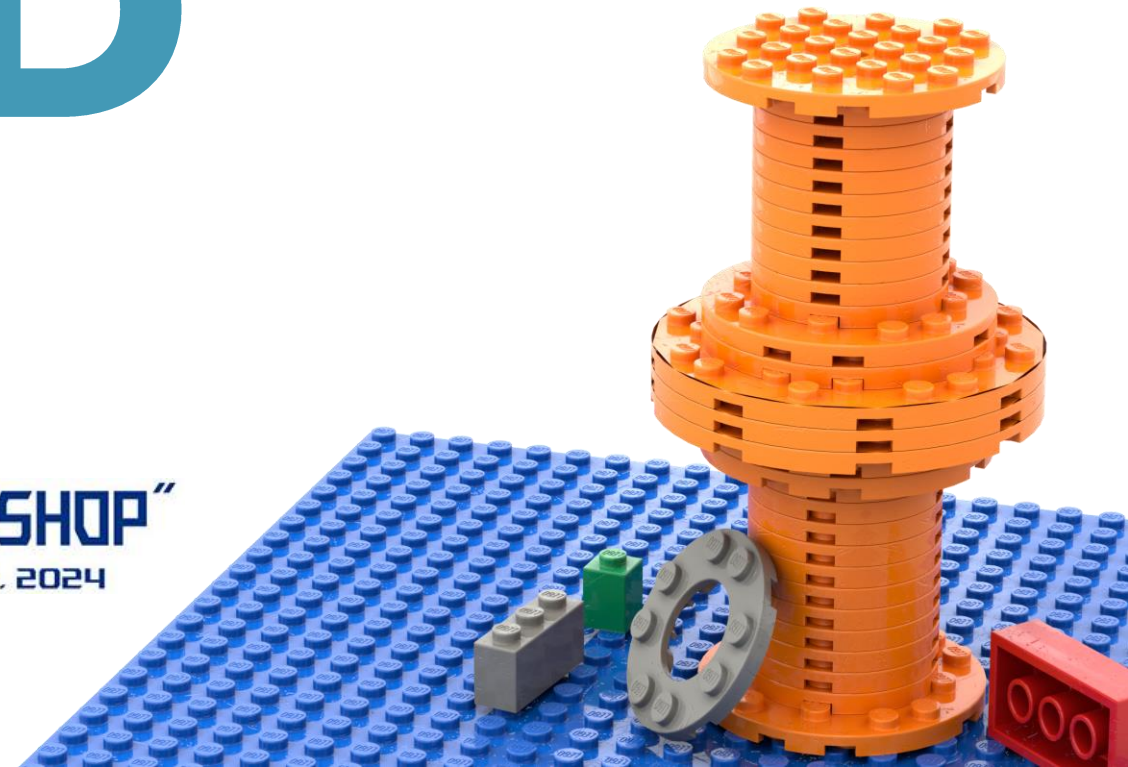
**INFN**  
LNL **Cristian Pira**

# SRF R&D



**2ND "FCC ITALY & FRANCE WORKSHOP"**

VENICE, PALAZZO FRANCHETTI - NOVEMBER 4 - 6, 2024



# Collaboration



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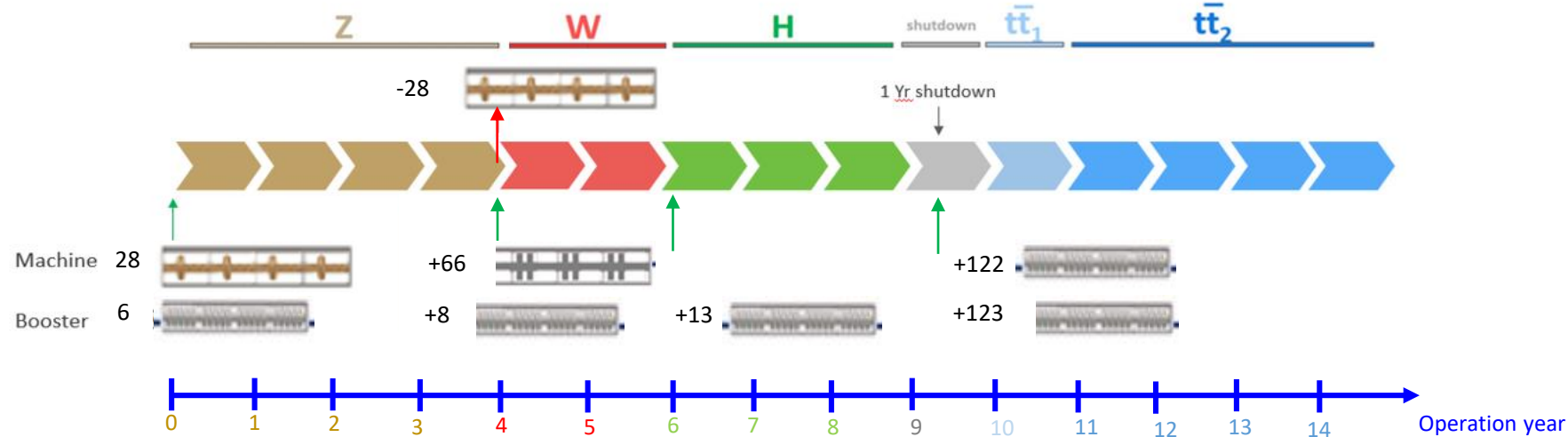
## Associated Partners

 A. M. Valente Feliciano

## Informal Partners



# SRF System Baseline for FCC



**In total: 366 CM, 1'464 cavities (4 cavities/CM, present assumption):**

- ▶ 400 MHz single-cell (Nb/Cu): 28 CM, 112 cavities → 4.5 K (to be removed after Z)
- ▶ 400 MHz two-cell (Nb/Cu): 66 CM, 264 cavities → 4.5 K
- ▶ 800 MHz five-cell (bulk Nb): 272 CM, 1'088 cavities → 2 K

**Collider** (ttbar2): 188 CM (264 cavities 400 MHz, 488 cavities 800 MHz)

**Booster** (ttbar2): 150 CM (600 cavities 800 MHz)

**Performance of thin film 400 MHz are one of the main challenges of FCC SRF System**

# 400 MHz requirements

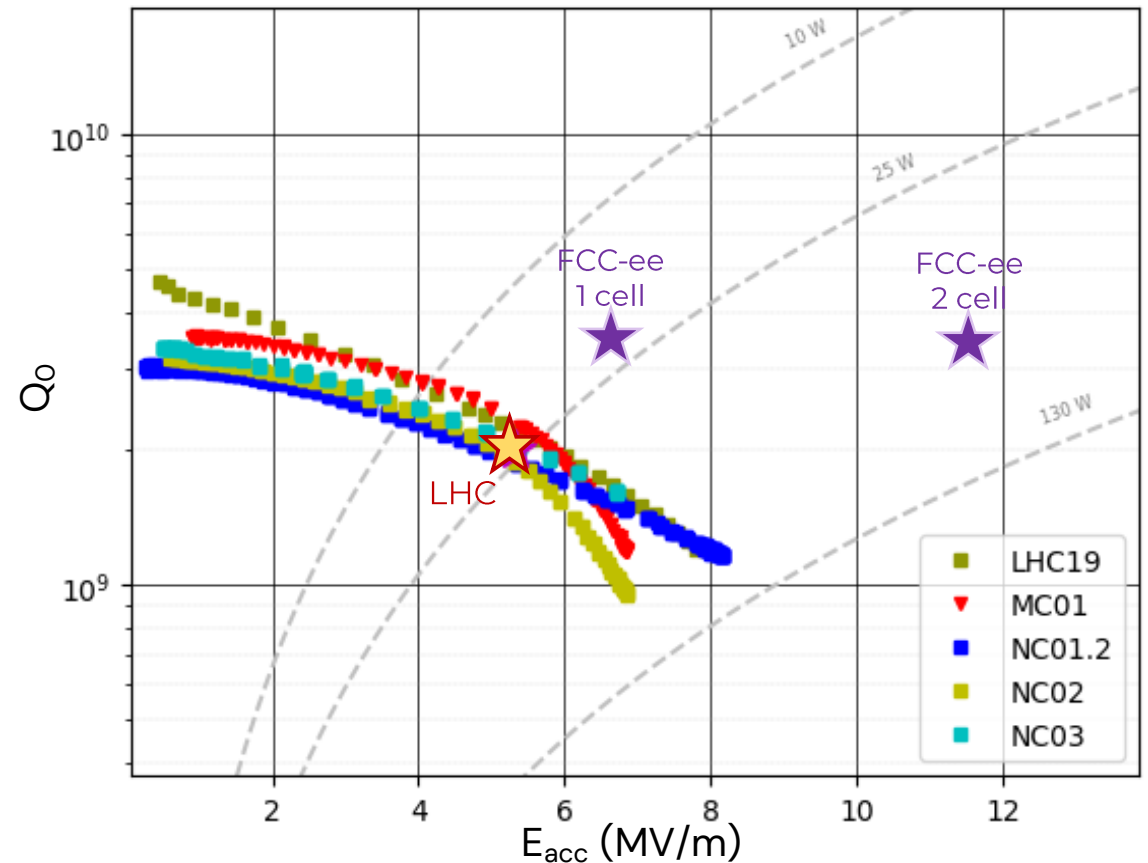


**FCC-ee** requires higher cavities performances than LHC

*Nb on Cu "baseline", Solid scheme with good margin for reliable operation Clear R&D paths identified (seamless copper cavities, HiPIMS coating, High Q0 bulk Nb cavities)*

*Franck Peauger, FCC week 2023*

LHC cavities Q vs  $E_{acc}$  @4.5 K

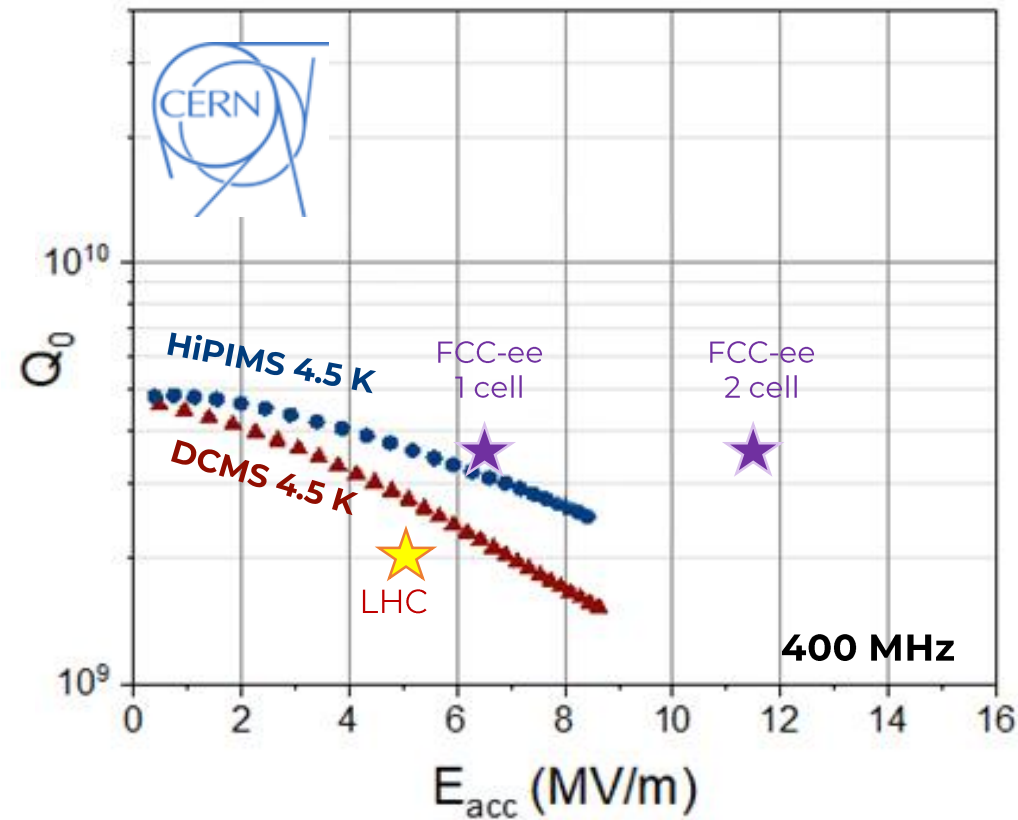
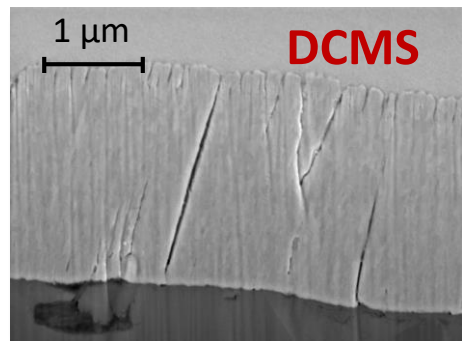
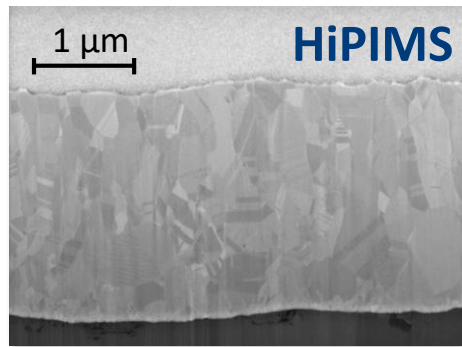


Graph from Carlota Pereira Carlos, FCC week 2023

# SRF R&D @CERN for FCC

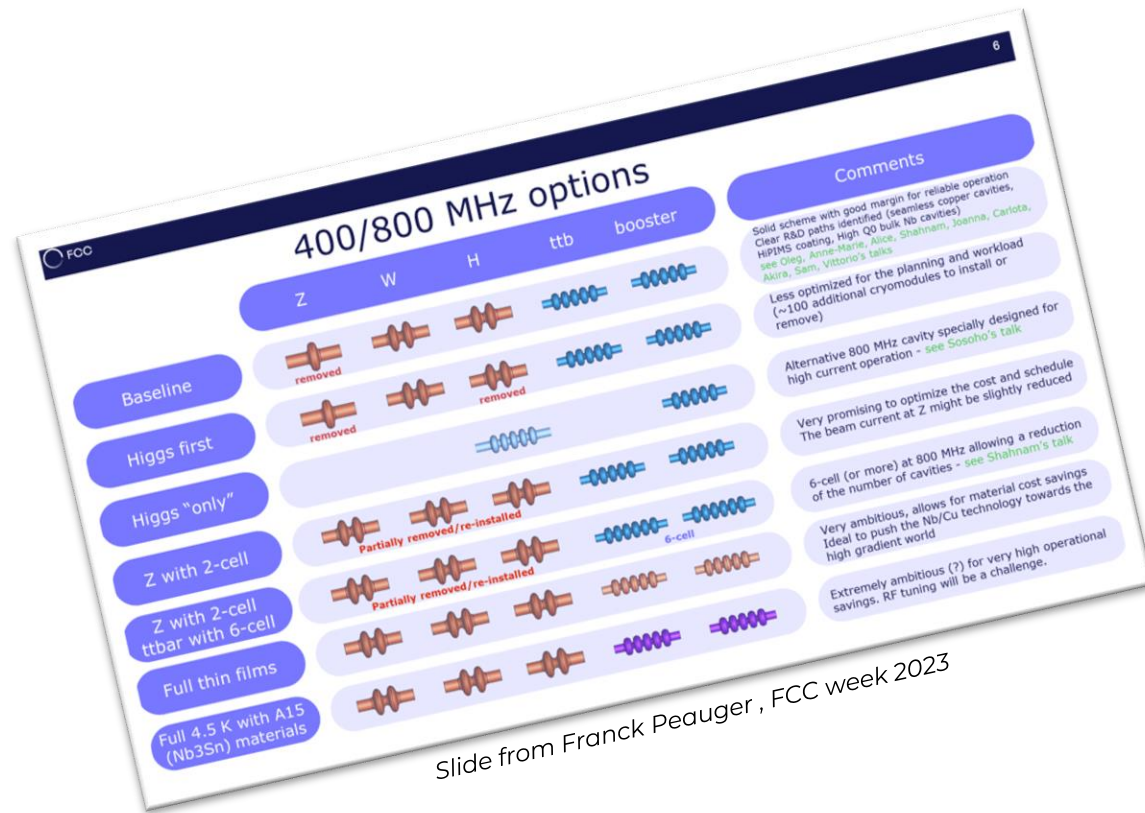
HiPIMS technology densifies the Nb coating and increases RF performances compared to DCMS

Carlota Pereira Carlos, FCC week 2023 (elaborated)



R&D @CERN also on cavity forming (hydroforming), polishing (EP), Cu oxide layer, Nb<sub>3</sub>Sn by HiPIMS

# Other Option for FCC SRF System



**Full 4.5 K with A15 Materials → Nb<sub>3</sub>Sn**

*Extremely ambitious for very high operational savings*

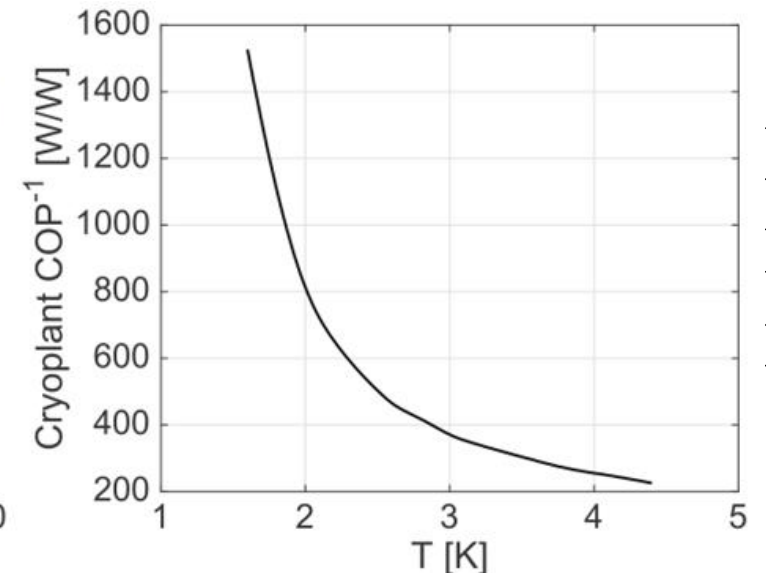
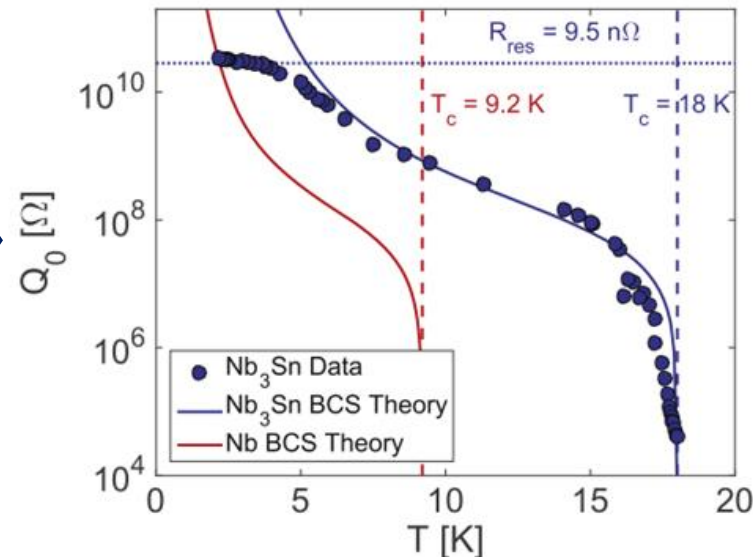
# Nb<sub>3</sub>Sn motivation

**Energy saving** is mandatory for the **next generation accelerators**

**Cryogenics** is one of the **larger energy cost** in modern SRF accelerators

➔ Move from **bulk Nb @2K** to **Nb<sub>3</sub>Sn @4.5 K**  
reduces cryogenic power by a factor of 3

7.5 GeV LINAC new construction



Supercond. Sci. Technol. 30 (2017) 033004

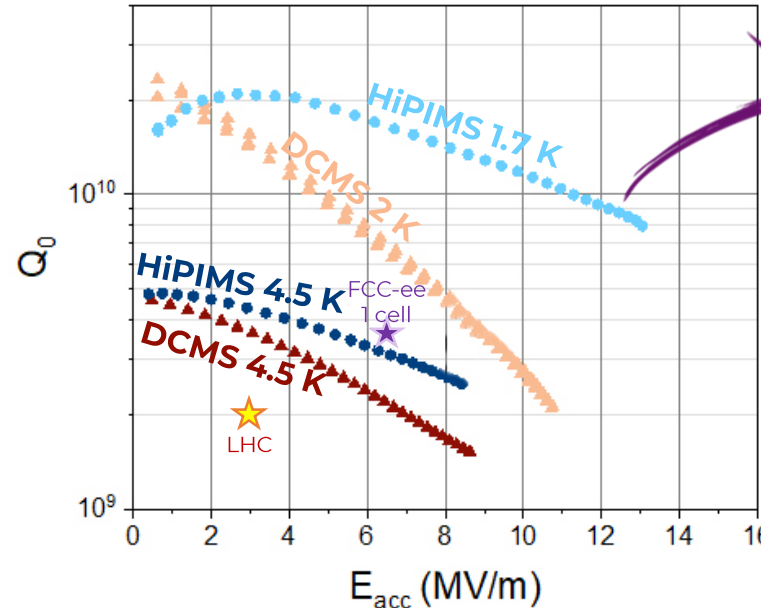
# Nb<sub>3</sub>Sn motivation

**Energy saving** is mandatory for the **next generation accelerators**

**Cryogenics** is one of the **larger energy cost** in modern SRF accelerators

Move from **thin film Nb @4.5 K** to **Nb<sub>3</sub>Sn @4.5 K**

Reduce  $T_{op}/T_c \rightarrow$  Suppress  $R_{BCS} \rightarrow$  Increase  $Q$



Expected Performances for Nb<sub>3</sub>Sn

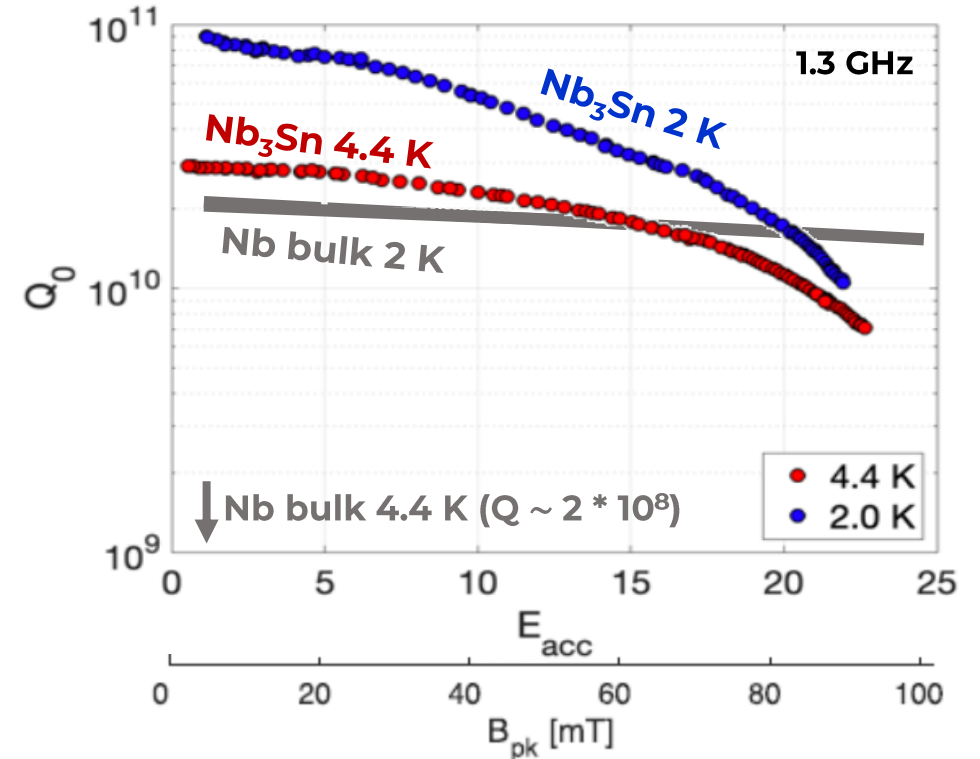
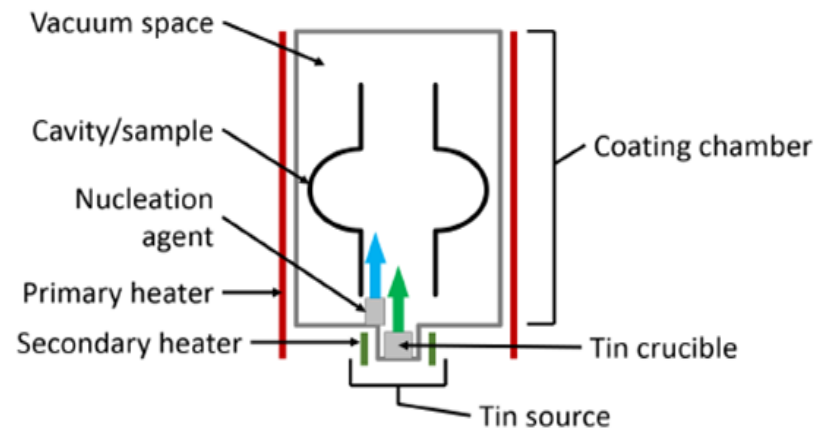
Carlota Pereira Carlos, FCC week 2023 (elaborated)



# Nb<sub>3</sub>Sn state of the art

## Vapor Tin Diffusion

Cornell, Fermilab, JLab, KEK



S. Posen, SRF 2019 proceedings (elaborated)

## Technology limitation:

- ▶ **Reproducibility**
- ▶ **Nb as Substrate** (expensive, chemistry, no interlayer possible)

# A different approach: $\text{Nb}_3\text{Sn}$ on Cu

## Cu substrate as several advantages:

- ▶ **Cheaper** than Nb
- ▶ Higher **thermal conductivity**
- ▶ Higher **mechanical stability**
- ▶ Low **carbon footprint**
- ▶ **PVD technology** (Nb on Cu) already used for LEP, LHC, HIE-ISOLDE @ CERN  
ALPI @ INFN LNL



# INFN LNL SRF R&D focused on Nb<sub>3</sub>Sn since 2021



The development of **Nb<sub>3</sub>Sn on Cu** for SRF accelerating cavities is part of **European Strategy** for Particle Physics Accelerator - **R&D Roadmap**

INFN R&D started in a CSN5 experiment



INFN LNL has a **leadership role** in the two main **European Projects** on Thin Film SRF R&D:



A **dedicated Project** on R&D of interest of FCC has been **financed by INFN board**:

**SRF cavities R&D for FCC-ee**

INFN Accelerators European Strategy Program

**RD\_FCC**  
INFN CSN1 Experiment

## International Partners:



# Nb<sub>3</sub>Sn on Cu: Multiple challenges

- ▶ A15 are Brittle materials
- ▶ Complicated Phase Diagram
- ▶ Low melting point substrate
- ▶ Interface diffusion
- ▶ Coating Parameters
- ▶ Substrate preparation
- ▶ Target Production/Magnetron Design
- ▶ Trapped Flux
- ▶ Tuning



# Nb<sub>3</sub>Sn on Cu: Multiple challenges

- ▶ Al5 are Brittle materials
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- ▶ **Coating Parameters**
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- ▶ **Target Production/Magnetron Design**
- ▶ **Trapped Flux**
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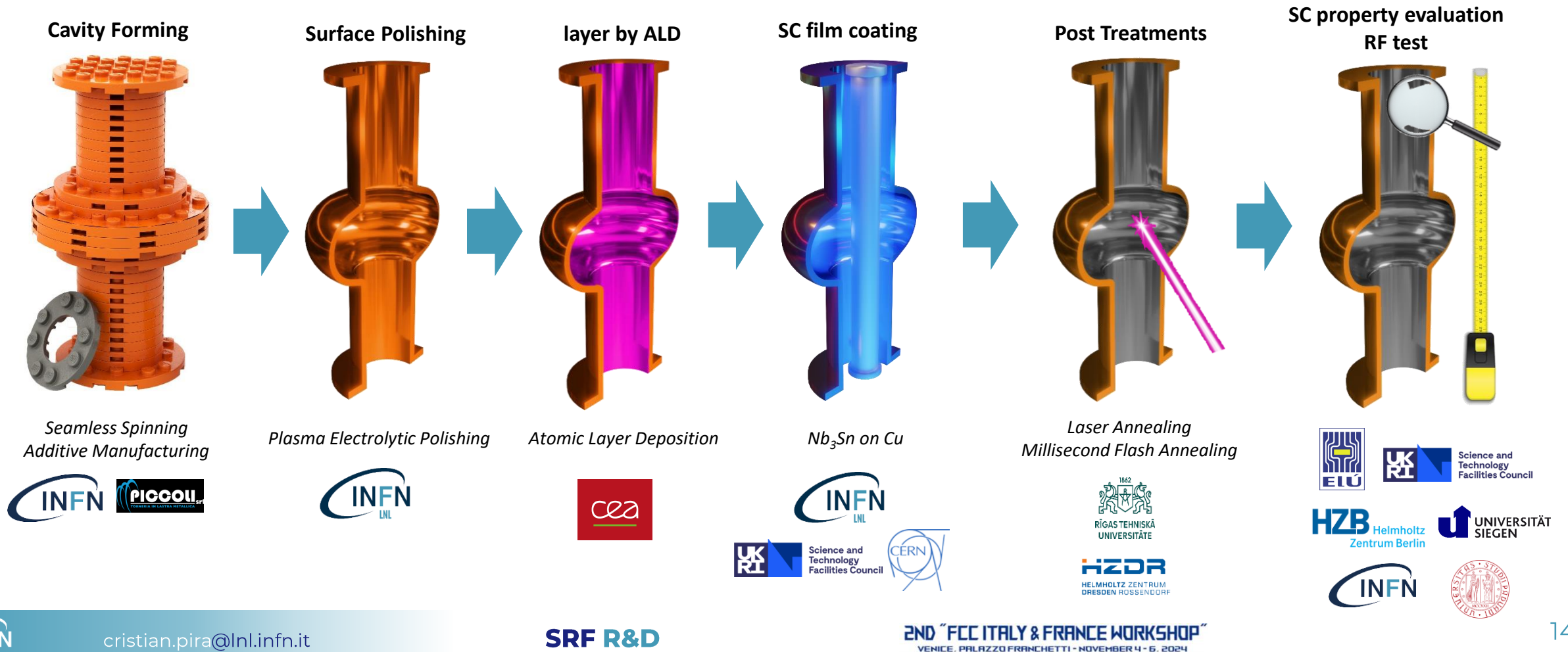


SRF cavities  
R&D for  
FCC-ee

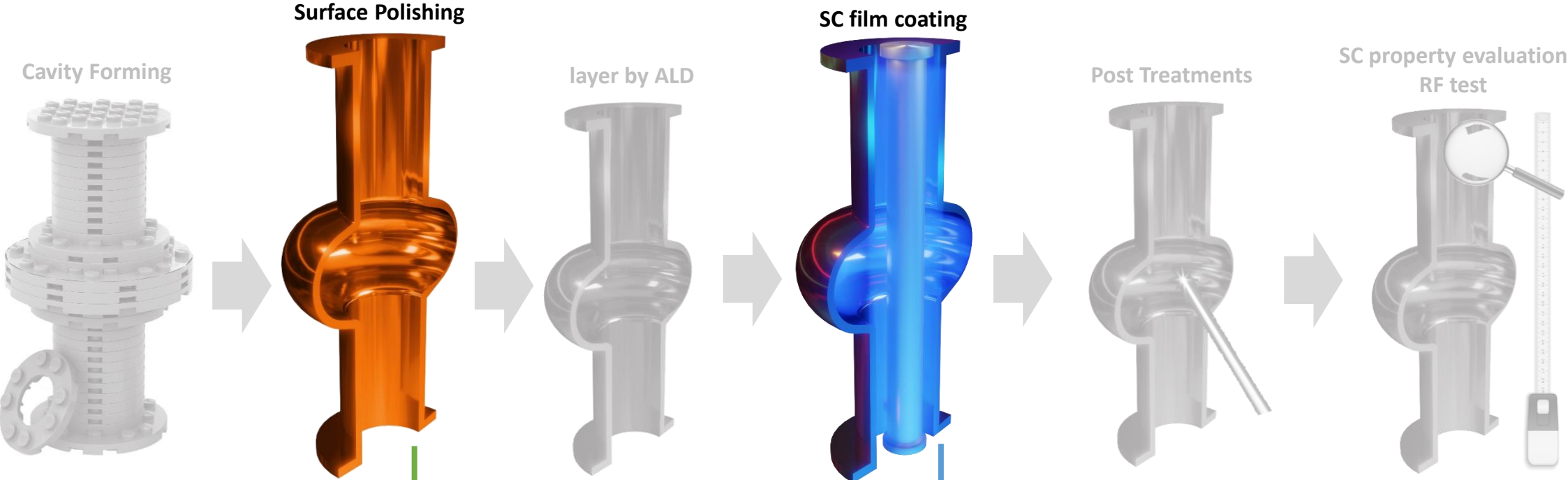
INFN Accelerators European  
Strategy Program



# Nb<sub>3</sub>Sn on Cu R&D activity covers all cavity production chain



# 2 Technologies in focus for FCC



Plasma  
Electrolytic  
Polishing



Nb<sub>3</sub>Sn on Cu  
Coatings

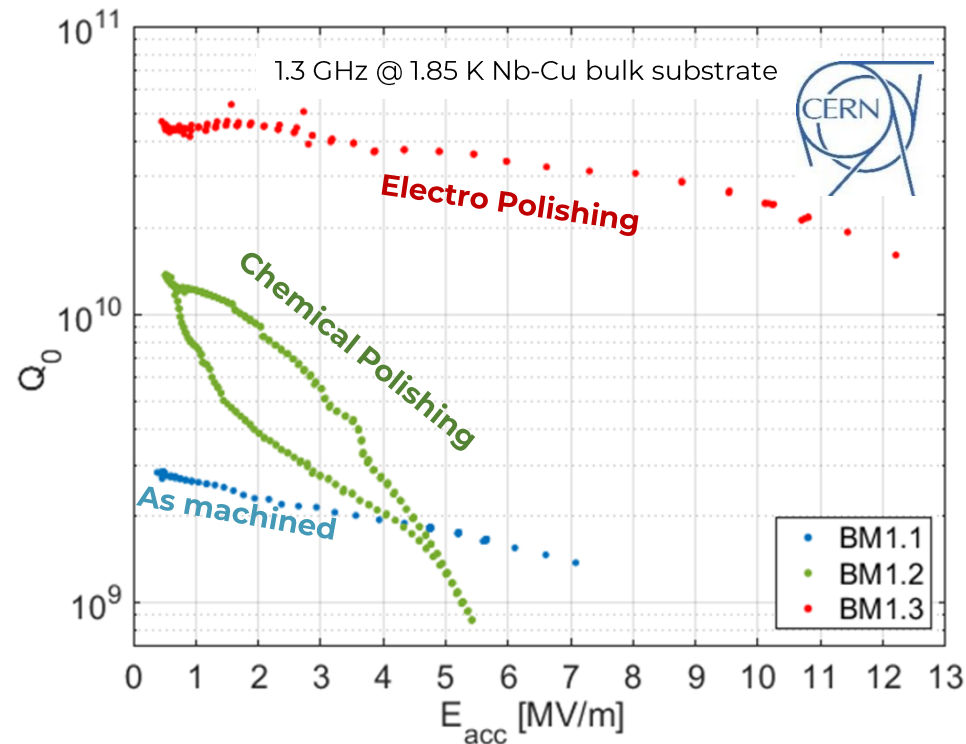


# Surface Polishing

## PEP



# Surface Polishing



L. Vega Cid, TTC meeting 2022 (elaborated)

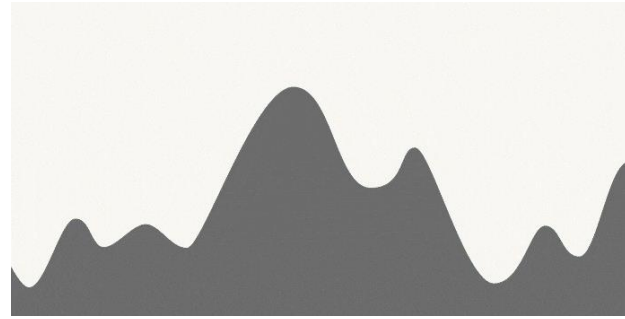
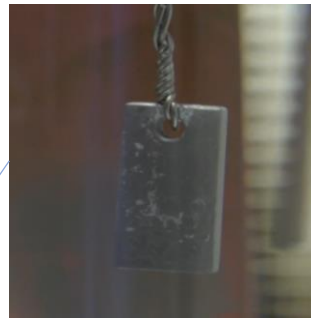
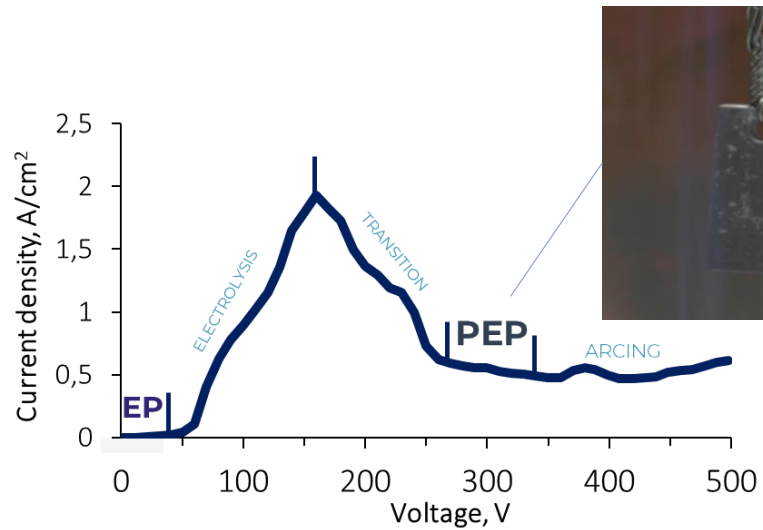
## Cu substrate plays a fundamental role in SRF performances

Roughness and defects reduction by **surface treatments are mandatory** for a good and uniform SRF coating

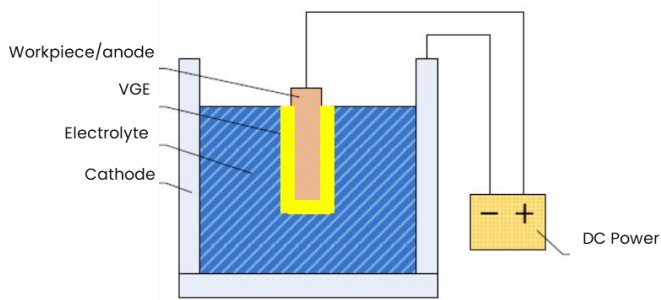
Cavity polishing requires **large amount of acids**. In particular **Nb** requires **HF** (extremely dangerous and poisoning process)



# Plasma Electrolytic Polishing PEP Mechanism



Same EP set-up  
Different regime



J. Wang et al., AMR, 2012

## Advantages



**Green**  
Diluted water solutions,  
environmentally friendly

**Fast**

The fastest  
non-destructive  
polishing

Equal thickness removal yield  
lowest roughness among  
competitors



**Efficiency**

**Plasma  
Electrolytic  
Polishing**

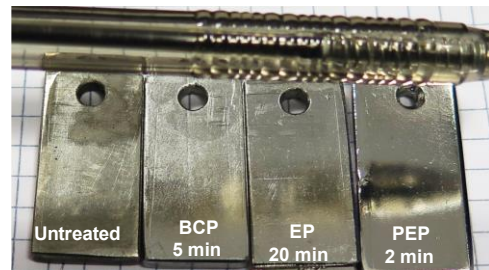
Less sensitive to the  
cathode shape!  
AM compatible

**Versatility**

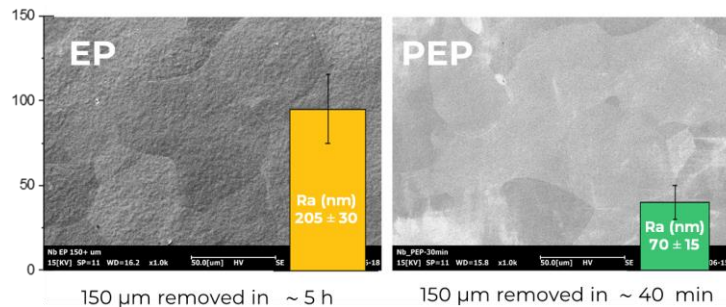
# Plasma Electrolytic Polishing **PEP** Results

1x Nb 3x Cu  
Solution Patents by INFN

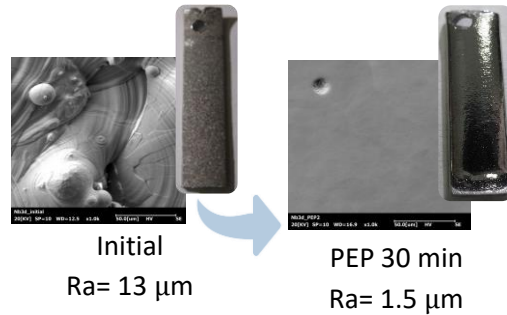
## Planar samples



6.5  $\mu$ m removed



## Additive Manufacturing



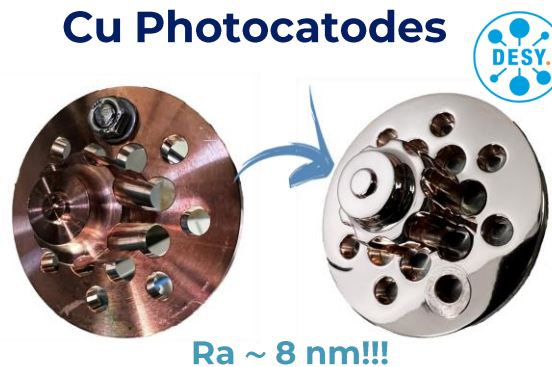
## QPR Samples



HZB Helmholtz Zentrum Berlin

## 6 GHz Cu cavity

## Cu Photocathodes



Ra ~ 8 nm!!!



**No internal cathode!**

70  $\mu$ m removed in 10 minutes  
30 A (100 cm<sup>2</sup> → 1.3 GHz ~ 300 A)

Courtesy of E. Chyhyrnyts

# Scale up to 1.3 GHz cavity successfully done! (Aug 2024)



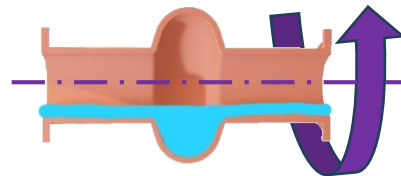
## Process Parameters

>150 um removed  
30 minutes! (EP→>12 hours)  
Voltage 300 V  
Current 90-190 A (0,06 – 0,13 A/cm<sup>2</sup>)  
Surface area 1400 cm<sup>2</sup>



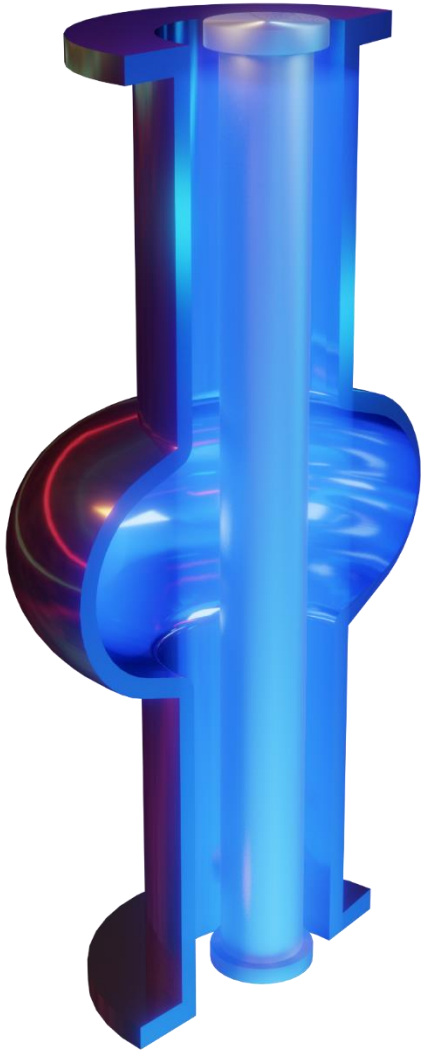
## Explore alternative set-up to reduce Process Power

- Reduce Treated Area (rotating cavity)
- Optimizing Process Parameters (Temperature, Voltage, ...)



## Next Steps:

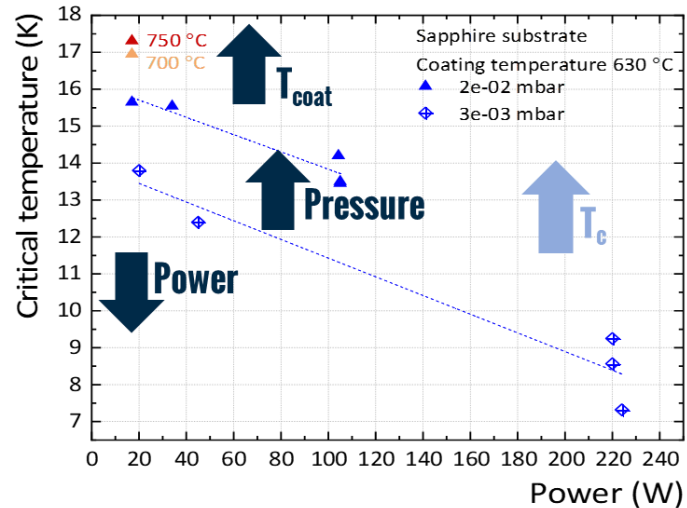
- Test **reproducibility**
- Validate with **RF Test** (Nb coating @CERN) → Feb 2025



# Nb<sub>3</sub>Sn on Cu Coatings

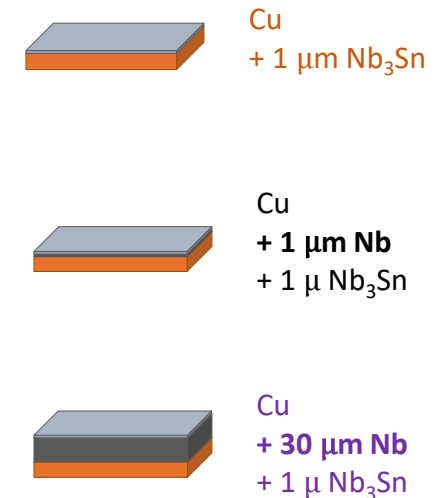
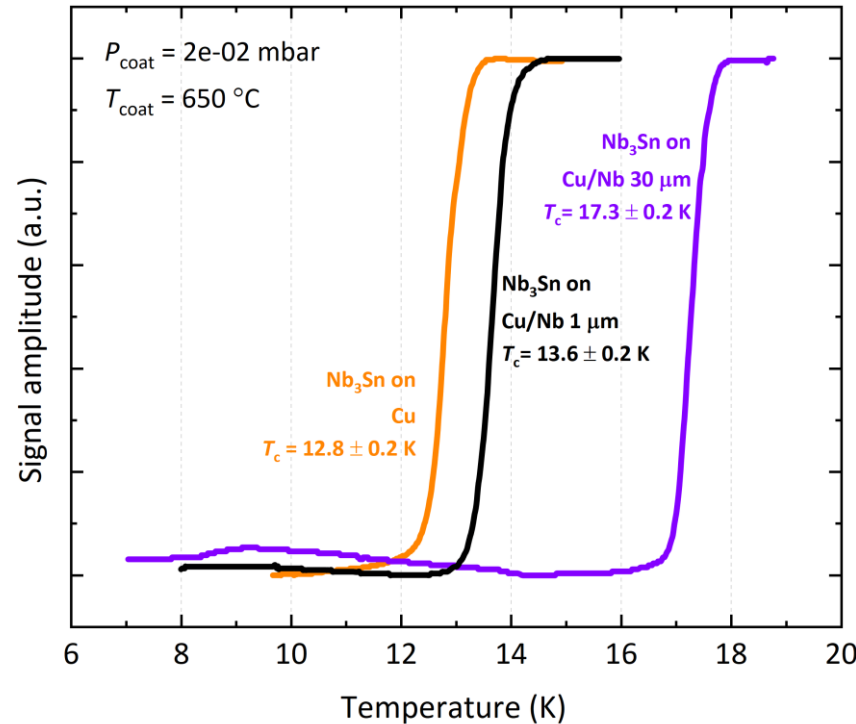
# Nb<sub>3</sub>Sn Coatings

Long R&D phase on PVD Parameter Optimization



## Optimized Coating Recipe

- Coating Parameters:
  - Pressure = 2\*10<sup>-2</sup> mbar
  - Power = 16 W
  - T substrate ≥ 600 C
- Nb Thick Barrier Layer > 30 um**



**A thick Nb buffer layer accommodates the Nb<sub>3</sub>Sn coating**

**Nb substrate can be used to validate Nb<sub>3</sub>Sn Coating Performances**

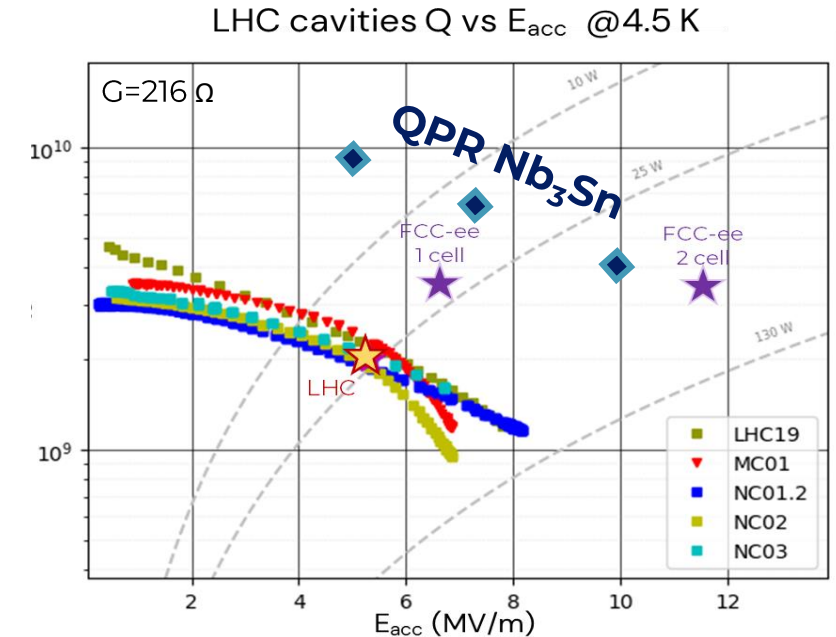
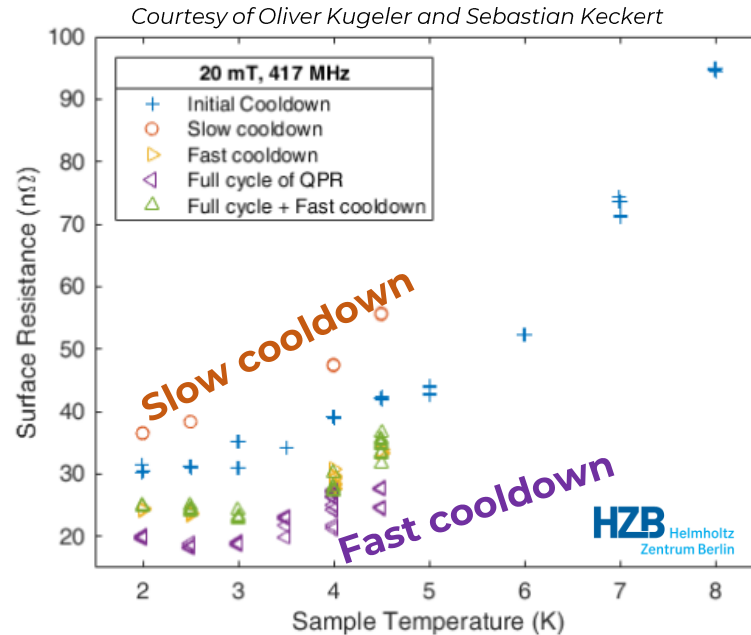
# First Nb<sub>3</sub>Sn RF Results

## (on a small Nb planar resonator)



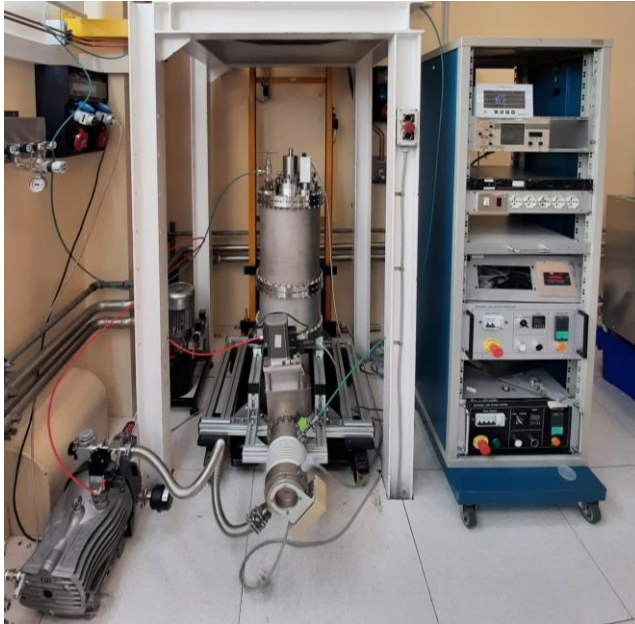
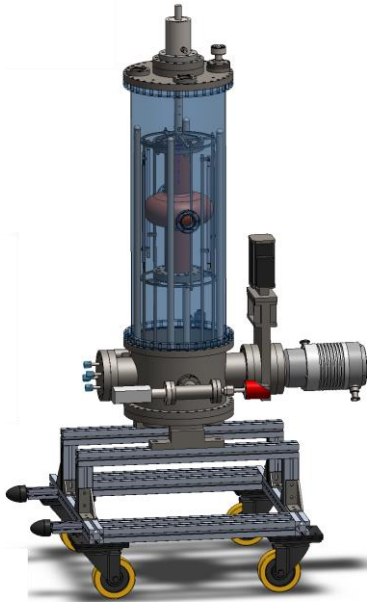
Rs of 23 nΩ @ 4.5 K, 20 mT      Quench >70 mT @ 4.5 K

- ▶ Nb<sub>3</sub>Sn coating suffer flux trapping
- ▶ Cooldown procedure influence Rs



Equivalent to a Q of  $9 \cdot 10^9$  @5 MV/m @4.5 K  
**5 times better than LHC → FCC-ee compatible**  
*Room for improvement*

# Nb<sub>3</sub>Sn Path to Final Prototype



**Nb<sub>3</sub>Sn on bulk Nb  
to validate coating performances  
on 1.3 GHz Elliptical Cavities (2025)**



**Develop Nb thick barrier/accommodation layer  
on 1.3 GHz Elliptical Cavities (2025)  
(proof of concept on 6 GHz cavities already done)**

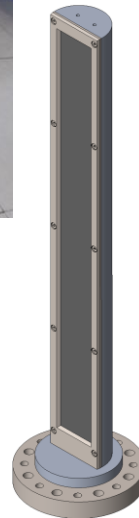
**Nb<sub>3</sub>Sn on Cu with thick Nb coating  
on 1.3 GHz Elliptical Cavities (2026-2028)**



*In parallel:*

- ▶ **1.3 GHz Vacuum system ready**
- ▶ **Magnetron source commissioned**

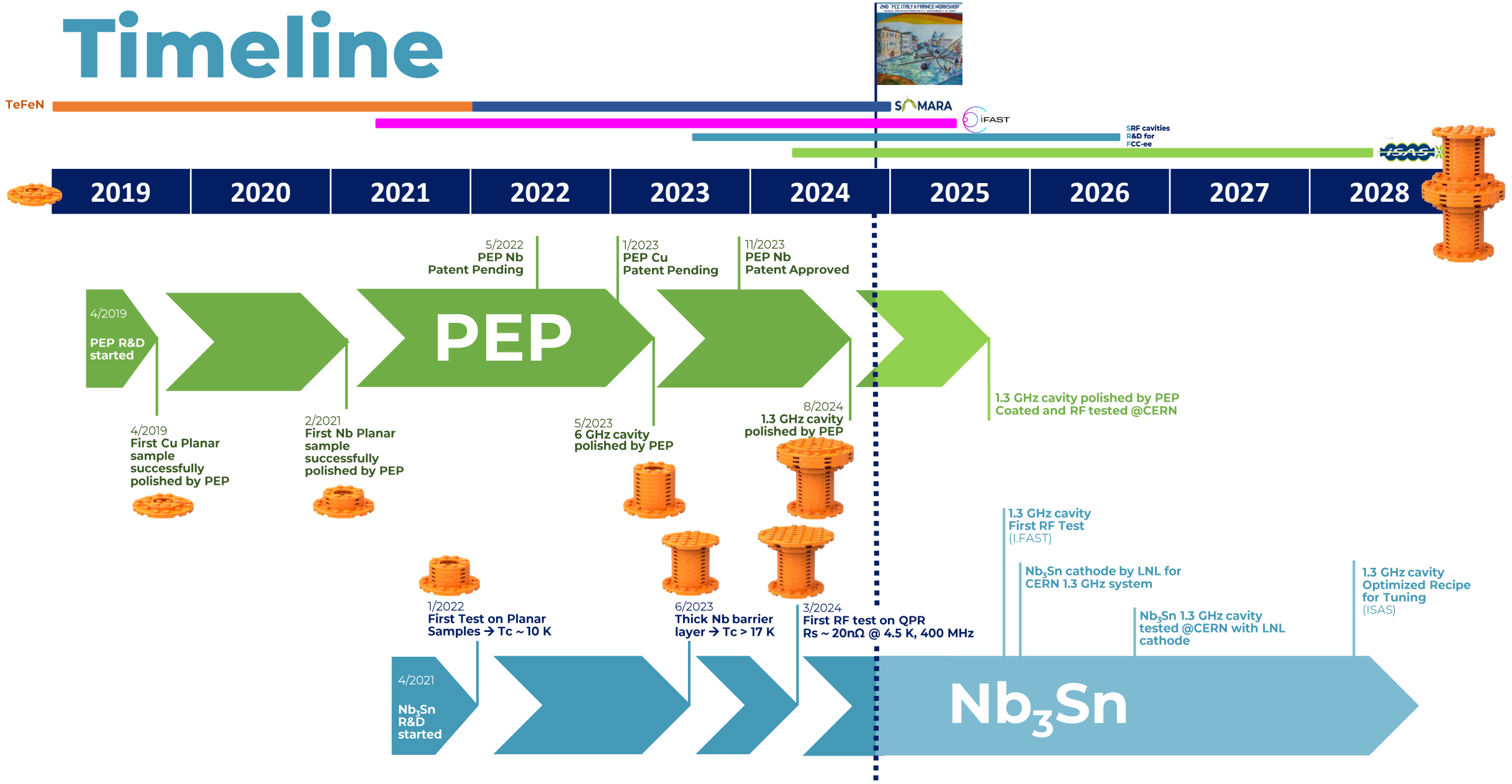
- ▶ *Study on alternative buffer layer*
- ▶ *Study on flux trapping*





# Timeline

TeFeN



# Conclusion

- ▶ **PEP and Nb<sub>3</sub>Sn films** are possible **game changer technologies** for SRF accelerating cavities
- ▶ **Big steps forward** in the last two years with transition from planar to 3D samples
- ▶ **Very promising results from first RF test**
- ▶ **Validation with 1.3 GHz cavities is necessary** prior to evaluating the feasibility of implementing these technologies in real accelerators
- ▶ **End of 2025** we expect to have the **first tests** available on **1.3 GHz cavities**
- ▶ **In 2028 optimized prototypes** are expected

Work supported by INFN CSN5 experiment SAMARA and INFN CSN1 experiments SRF and RD\_FCC

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# Thank you!





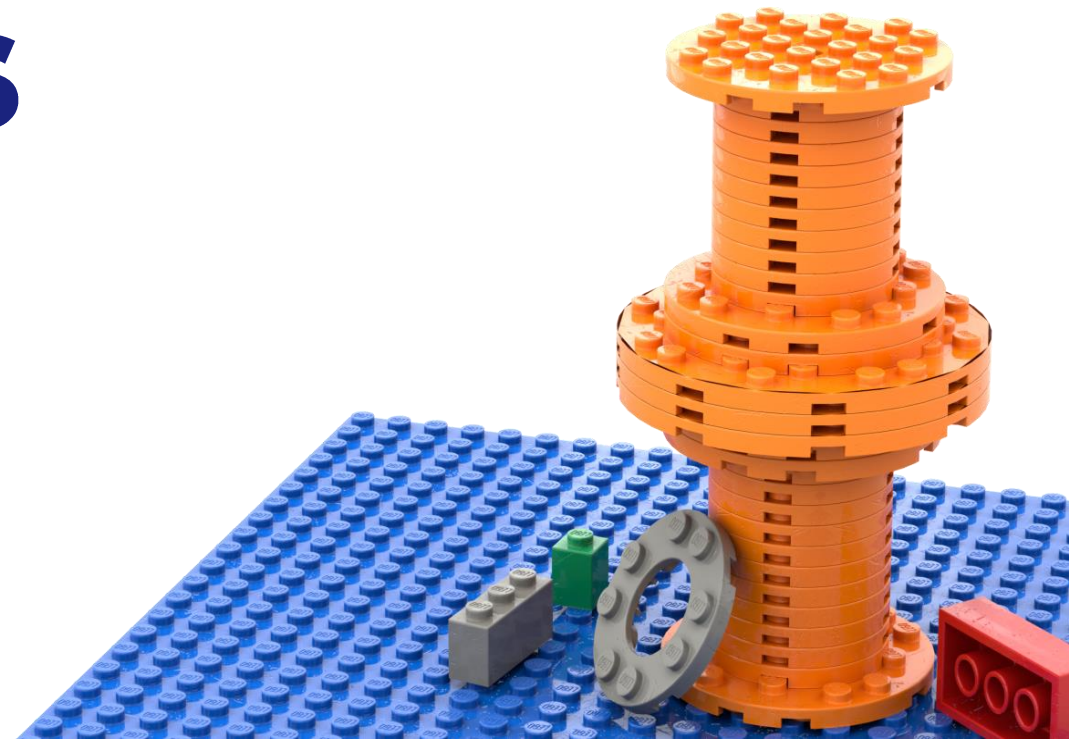
Cristian Pira

# Backup Slides

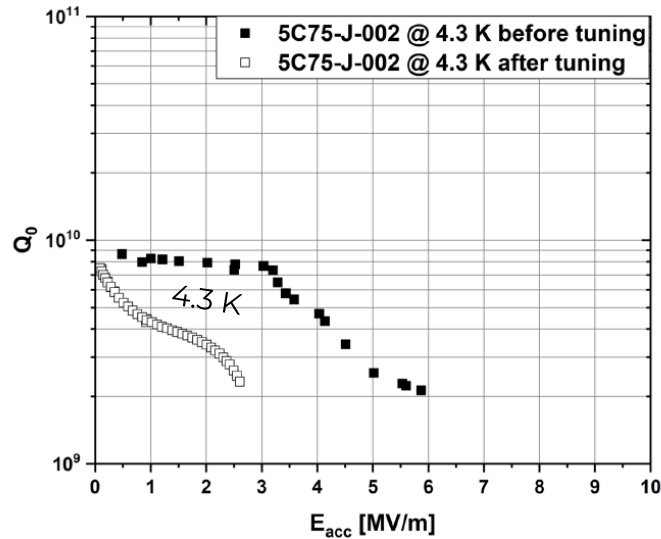
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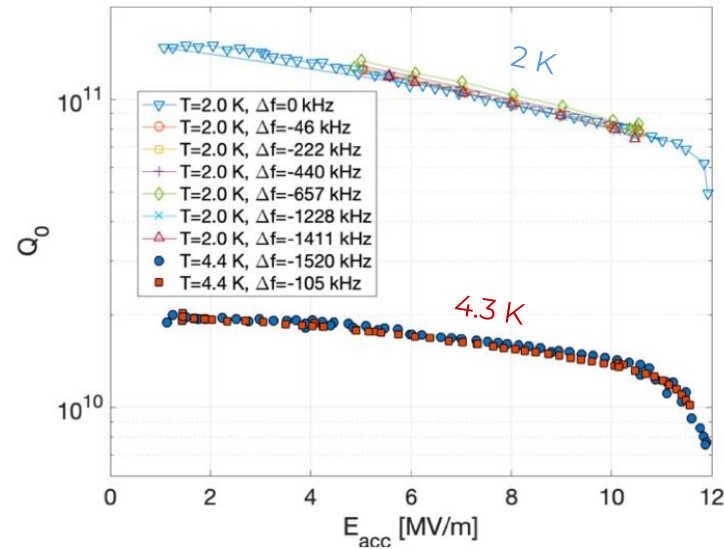
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# Cavity Tunability



**Strong performance degradation** after room temperature tuning for 200 kHz



**Little change** in the coated cavity performance after tuning up to 1400 kHz at cryogenic temperatures

## Nb<sub>3</sub>Sn is extremely brittle

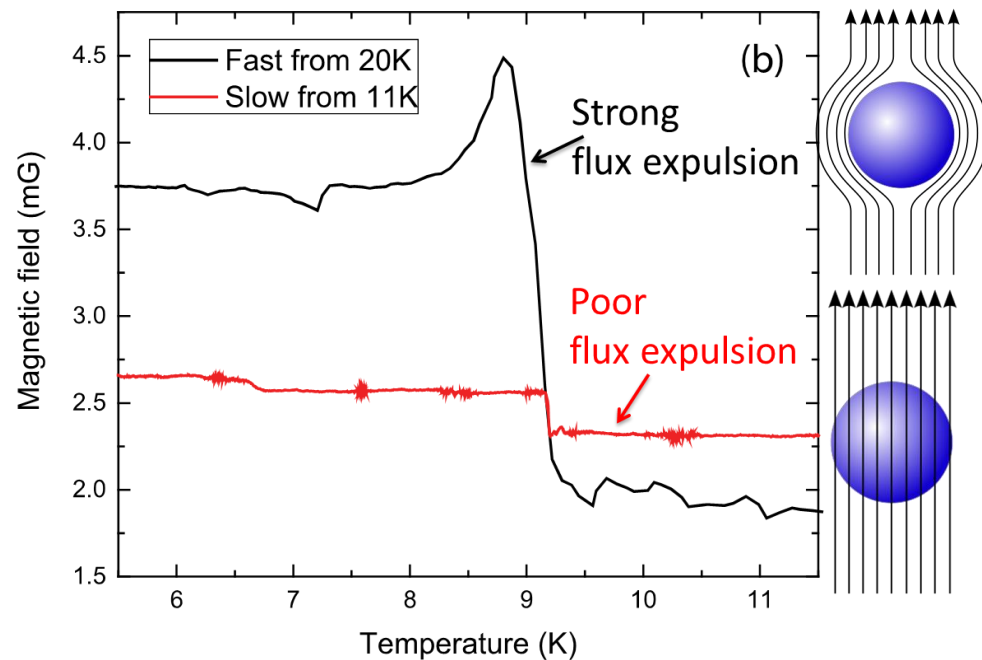
Eremeev, G. (2023). Tunability/robustness of Nb<sub>3</sub>Sn (No. FERMILAB-SLIDES-23-402-TD). Fermi National Accelerator Laboratory (FNAL), Batavia, IL (United States).

- ▶ Vapor Tin Diffusion Nb<sub>3</sub>Sn on Nb cavities can be tuned only at cryogenic T
- ▶ An interlayer in Nb<sub>3</sub>Sn on Cu coatings can be added to enhance film mechanical stability and tunability

# Trapped Flux

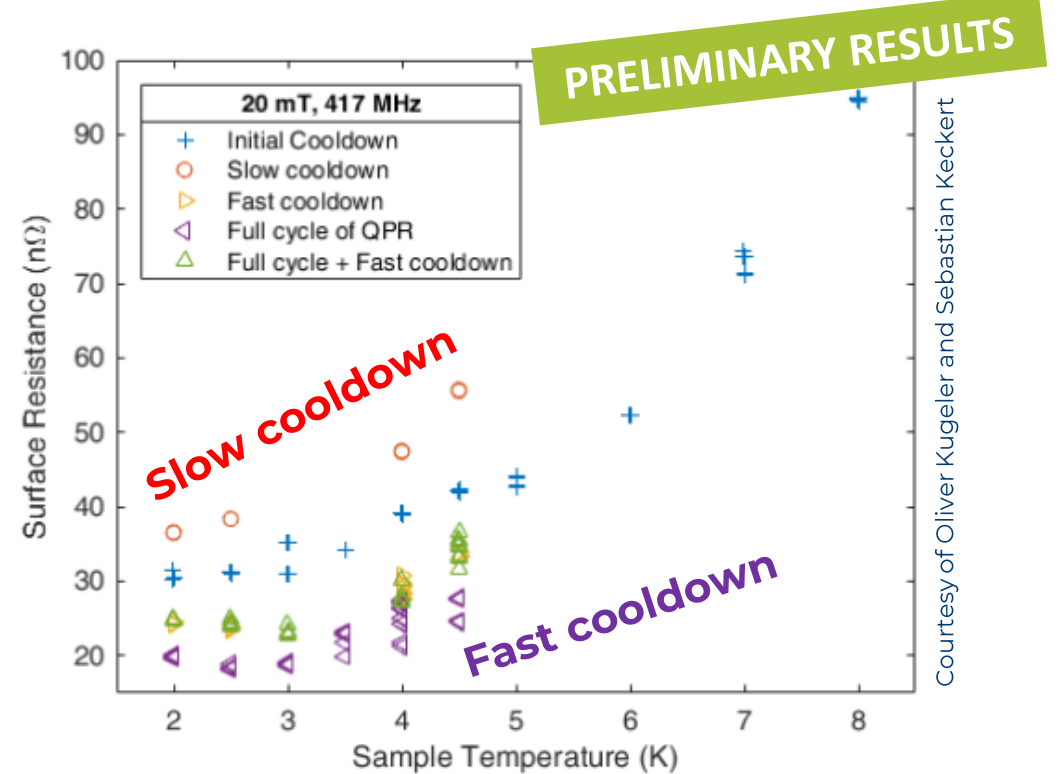
$$Q_0 \propto \frac{1}{R_{BCS} + R_{res} + \eta S B}$$

Fraction of Trapped Flux      Sensitivity



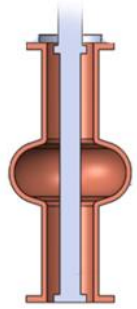
A. Romanenko, A. Grassellino, O. Melnychuk, D. A. Sergatskov, *J. Appl. Phys.* 115, 184903 (2014)

## First ISAS Results:



- ▶ **Nb<sub>3</sub>Sn coating suffer flux trapping**
- ▶ **Cooldown procedure influence Rs**

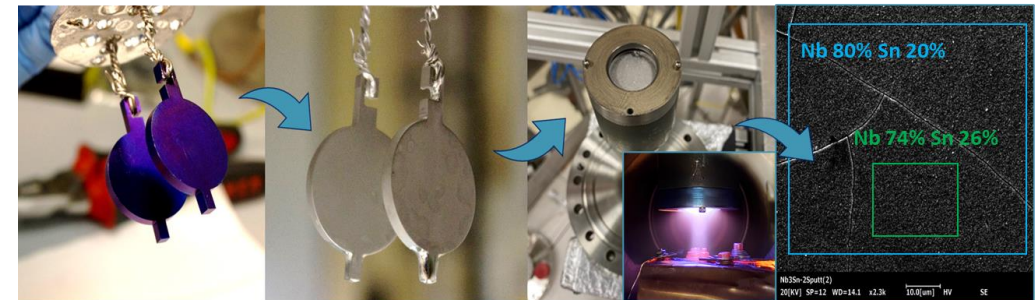
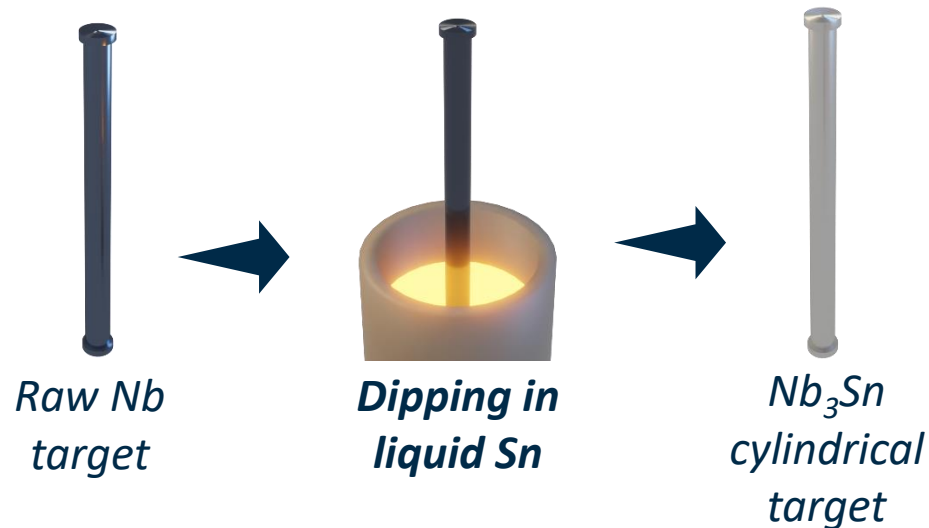
# Nb<sub>3</sub>Sn coatings: target production



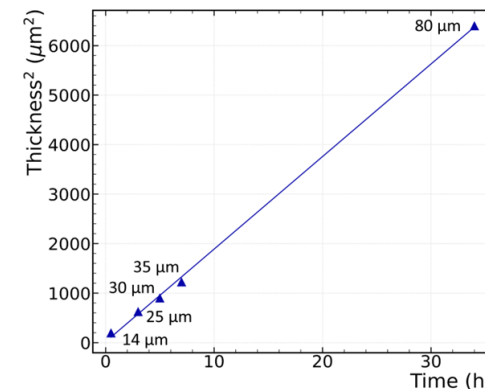
Single target configuration **easiest to scale** onto elliptical geometry

Nb<sub>3</sub>Sn cylindrical targets are not commercially available

## LNL Strategy for Nb<sub>3</sub>Sn cylindrical targets production for 6 GHz cavities



Proof of concept

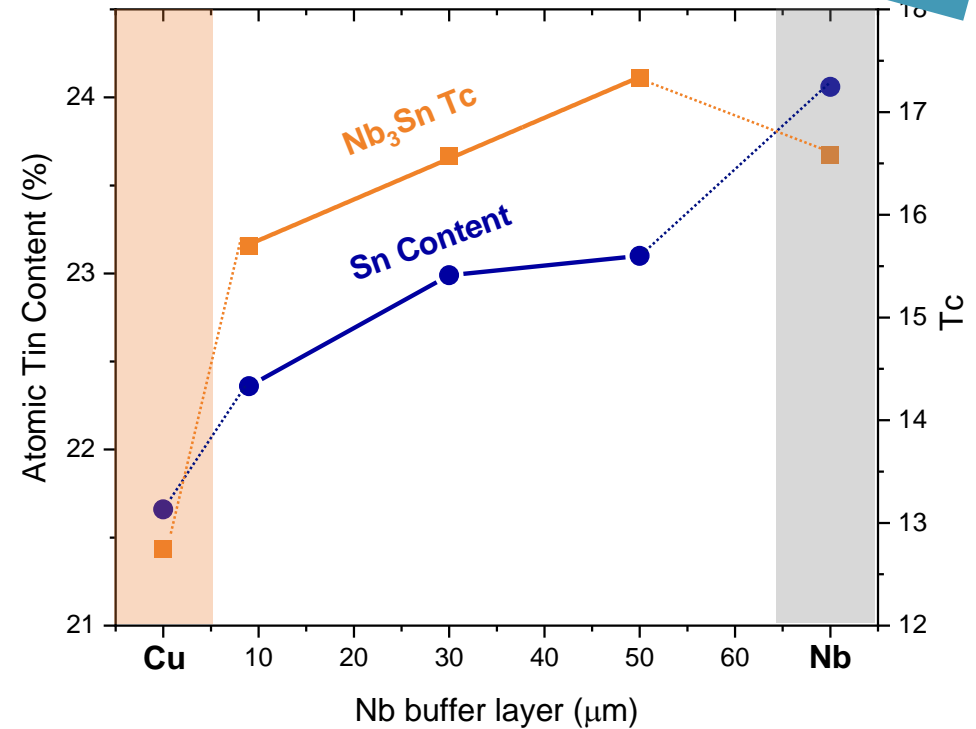
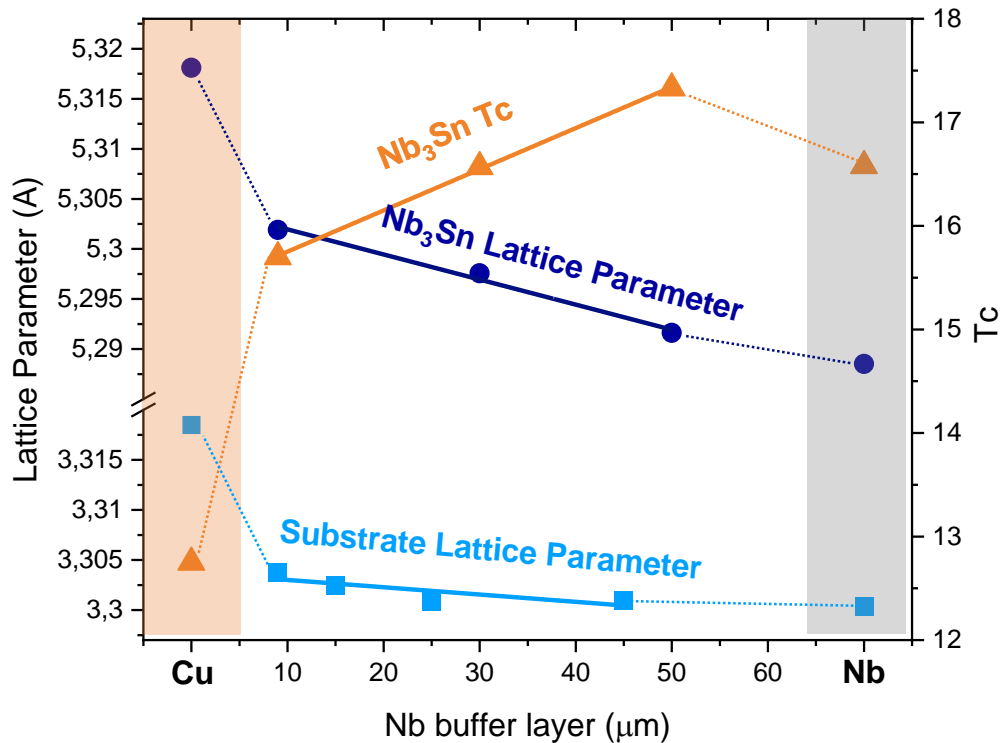


Nb<sub>3</sub>Sn **thickness** related to **dipping time**

Possible **tin content modulation**

# Nb<sub>3</sub>Sn coatings

## Sputtering parameter optimization



The role of the thick Nb layer is to accommodate the Nb<sub>3</sub>Sn lattice parameter

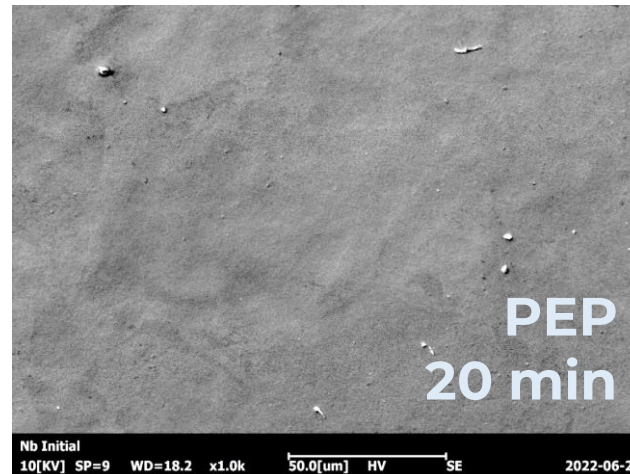
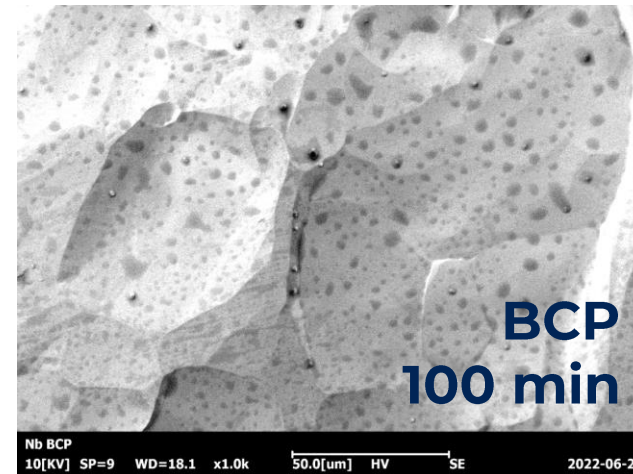
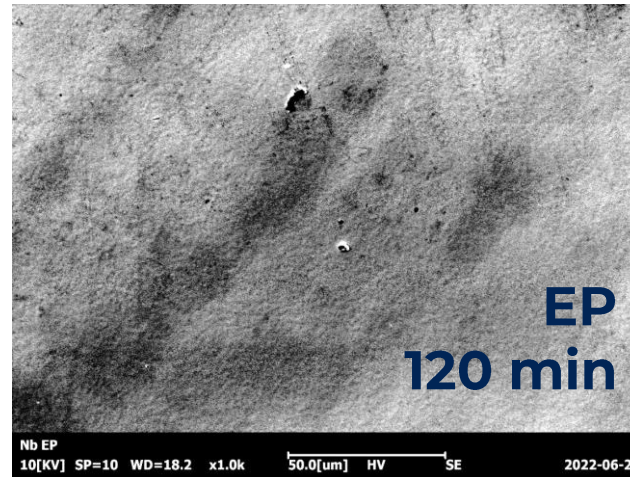
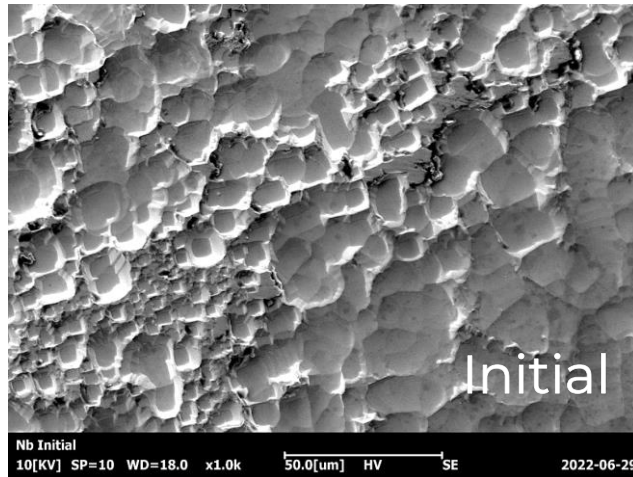
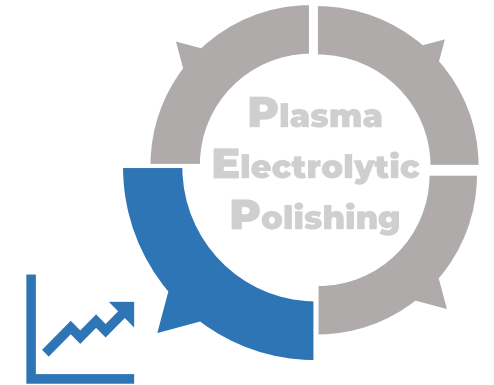


ALD layer could be an alternative to explore

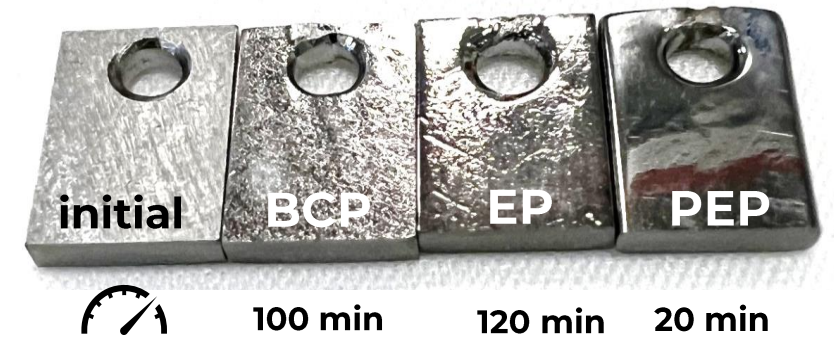


# PEP is Efficient

## Comparison with EP and BCP



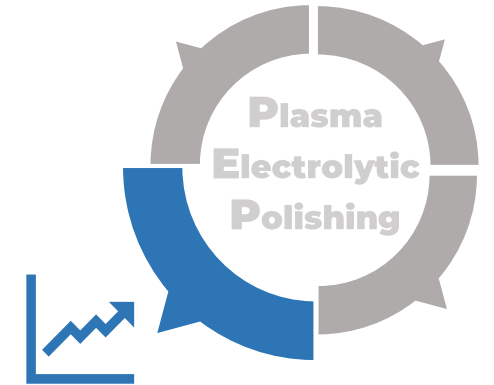
Nb, Magnification **1000x**;  
100  $\mu\text{m}$  Removal



Both micro and macro  
**roughness is improved significantly**

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## Comparison with EP and BCP



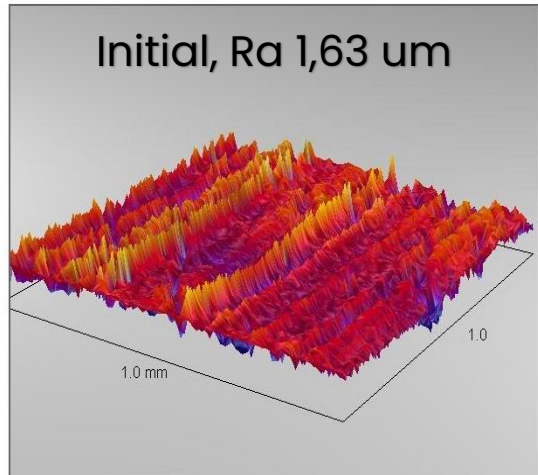
Dektak 8

Surface Stats:

Ra: 1.63  $\mu\text{m}$   
 Rq: 2.11  $\mu\text{m}$   
 Rt: 16.92  $\mu\text{m}$

Measurement Info:

Sampling: 222.22 nm  
 Array Size: 4500 X 315



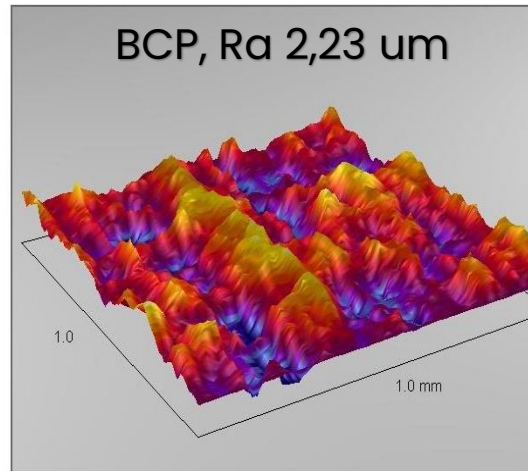
Dektak 8

Surface Stats:

Ra: 2.23  $\mu\text{m}$   
 Rq: 2.73  $\mu\text{m}$   
 Rt: 5.02  $\mu\text{m}$

Measurement Info:

Sampling: 222.22 nm  
 Array Size: 4500 X 316



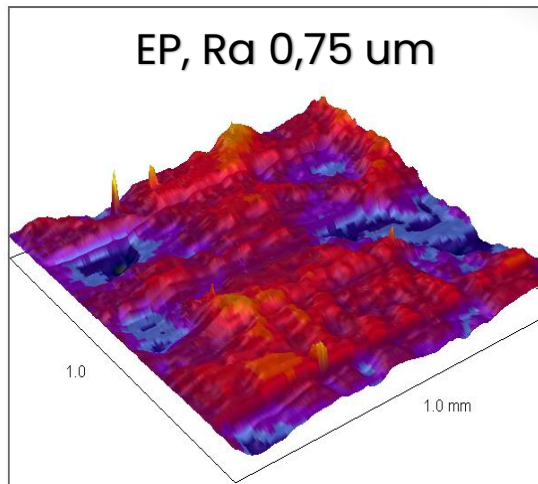
Dektak 8

Surface Stats:

Ra: 750.04 nm  
 Rq: 927.93 nm  
 Rt: 7.81  $\mu\text{m}$

Measurement Info:

Sampling: 333.33 nm  
 Array Size: 3000 X 316



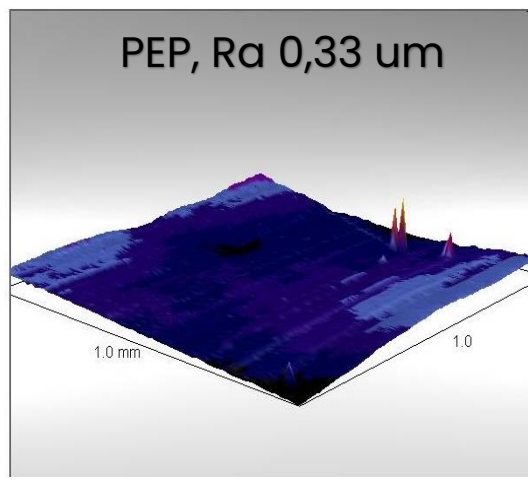
Dektak 8

Surface Stats:

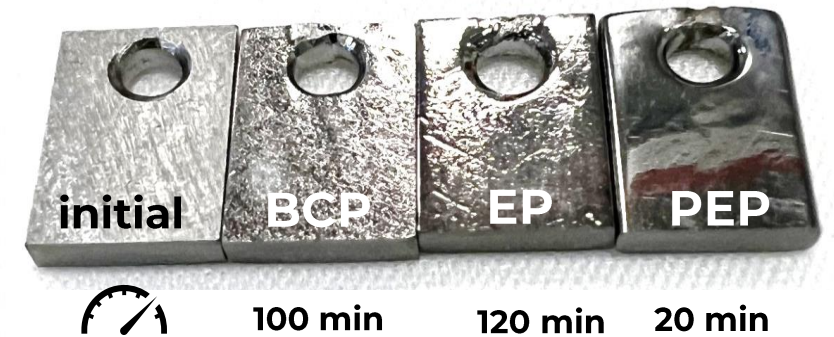
Ra: 0.33  $\mu\text{m}$   
 Rq: 0.43  $\mu\text{m}$   
 Rt: 1.18  $\mu\text{m}$

Measurement Info:

Sampling: 222.22 nm  
 Array Size: 4500 X 316



Nb, Magnification **1000x**;  
 100  $\mu\text{m}$  Removal



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**roughness is improved significantly**

# Comparison

## Copper treatments

Process / parameters	"SUBU5"	EP (3:2)	PEP in "SUBU5"
Solution composition	Sulfamic acid 5 g/l; NH <sub>4</sub> -citrate 1 g/l Butanol 50 ml/l; H <sub>2</sub> O <sub>2</sub> 50 ml/l	85 % H <sub>3</sub> PO <sub>4</sub> 60 p. 99% n-Butanol 40p.	Sulfamic acid 5 g/l; NH <sub>4</sub> -citrate 1 g/l Butanol 50 ml/l; H <sub>2</sub> O <sub>2</sub> 50 ml/l
Voltage	-	2-6 V	300 V
Current density	-	0,01 – 0,03 A/cm <sup>2</sup>	0,25-0,8 A/cm <sup>2</sup>
Power draw	-	0,06 – 0,18 W/cm <sup>2</sup>	75 – 240 W/cm <sup>2</sup>
Removing rate	1,5 μm/min (70±2 °C)	0,15-0,5 μm/min (25 °C)	20-30 μm/min (80 °C)